

Docket No.: 49657-961



*Jfw* 2882  
PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of	:	Customer Number: 20277
Kenji ITOGA, et al.	:	Confirmation Number: 5521
Application No.: 09/769,490	:	Group Art Unit: 2882
Filed: January 26, 2001	:	Examiner: C. Kao
For:	:	
X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK, X-RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON RADIATION METHOD AND SEMICONDUCTOR DEVICE		

**AMENDMENT**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

The following Amendment and Remarks are submitted in response to the Office Action  
dated April 13, 2004.

08/13/2004 EABUBAK1 00000121 500417 09769490

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